



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Frank Y. Xu et al.
App. No.: 10/789,319 GPAU: 1712
Filing Date: 02/27/2004 Examiner: Marc S. Zimmer
Dkt. No.: P121-63-03 Conf. No.: 9202
For: COMPOSITION FOR AN ETCHING MASK COMPRISING A SILICON-
CONTAINING MATERIAL

INFORMATION DISCLOSURE STATEMENT

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure and pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. The undersigned brings the patents, publications, applications or other information identified in the attached:

- ☒ Form(s) PTO/SB/08A and/or PTO/SB/08B or PTO/1449
☐ Other:

to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed: before the mailing date of a first Office action on the merits or before the mailing date of a first Office action after the filing of a request for continued examination under § 1.114. Therefore, no fee is believed required.

Applicant(s) does not believe that any additional fees are due, but if the Commissioner believes additional fees are due,

the Commissioner is hereby authorized to charge any fees which may be required, or credit any overpayment, to Deposit Account Number 502650.

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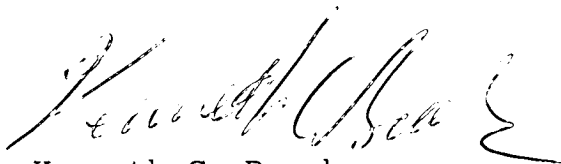
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1/5/09

Respectfully Submitted,



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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

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of

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Complete if Known

Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
	A1	3,527,062		Belinski et al.	09-08-1970	
	A2	3,783,520		King	01-08-1974	
	A3	3,807,027		Heisler	04-30-1974	
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	A5	3,811,665		Seelig	05-21-1974	
	A6	4,062,600		Wyse	12-13-1977	
	A7	4,070,116		Frosch et al.	01-24-1978	
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	A10	4,155,169		Drake et al.	05-22-1979	
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	A19	4,440,804		Milgram	04-03-1984	
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	A33	4,737,425		Lin et al.	04-12-1988	
	A34	4,763,886		Takei	08-16-1988	
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			Group Art Unit	1712	
			Examiner Name	Zimmer, Marc S.	
Sheet	2	of	25	Attorney Docket Number	P121-63-03

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		Number	Kind Code ² (if known)			
	A35	4,772,878		Kane	09-20-1988	
	A36	4,808,511		Holmes	02-28-1989	
	A37	4,826,943		Ito et al.	05-02-1989	
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	A42	4,883,561		Gmitter et al.	11-28-1989	
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	A44	4,891,303		Garza et al.	01-02-1990	
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	A47	4,919,748		Bredbenner et al.	04-24-1990	
	A48	4,921,778		Thackeray et al.	05-01-1990	
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	A50	4,931,351		McColgin et al.	06-05-1990	
	A51	4,959,252		Bonnebat et al.	09-25-1990	
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	A65	5,126,006		Cronin et al.	06-30-1992	
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		Number	Kind Code ² (if known)			
	A69	5,155,749		DiMilia et al.	10-13-1992	
	A70	5,169,494		Hashimoto et al.	12-08-1992	
	A71	5,171,490		Fudin	12-15-1992	
	A72	5,173,393		Sezi et al.	12-22-1992	
	A73	5,179,863		Uchida et al.	01-19-1993	
	A74	5,198,326		Hashimoto et al.	03-30-1993	
	A75	5,204,739		Domenicali	04-20-1993	
	A76	5,206,983		Guckel et al.	05-04-1993	
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	A78	5,218,193		Miyatake	06-08-1993	
	A79	5,234,793		Sebald et al.	08-10-1993	
	A80	5,240,550		Boehnke et al.	08-31-1993	
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	A87	5,314,772		Kozicki et al.	05-24-1994	
	A88	5,318,870		Hartney	06-07-1994	
	A89	5,324,683		Fitch et al.	06-28-1994	
	A90	5,328,810		Lowrey et al.	07-12-1994	
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	A92	5,348,616		Hartman et al.	09-20-1994	
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	A94	5,357,122		Okubora et al.	10-18-1994	
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	A101	5,414,514		Smith et al.	05-09-1995	
	A102	5,417,802		Obeng	05-23-1995	
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Sheet

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		Number	Kind Code ² (if known)			
	A103	5,421,981		Leader et al.	06-06-1995	
	A104	5,422,295		CHOI et al.	06-06-1995	
	A105	5,424,549		Feldman	06-13-1995	
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	A111	5,453,157		Jeng	09-26-1995	
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	A114	5,480,047		Tanigawa et al.	01-02-1996	
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	A119	5,515,167		Ledger et al.	05-07-1996	
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	A127	5,669,303		Maracas et al.	09-23-1997	
	A128	5,670,415		Rust	09-23-1997	
	A129	5,700,626		Lee et al.	12-23-1997	
	A130	5,723,176		Keyworth et al.	03-03-1998	
	A131	5,724,145		Kondo et al.	03-03-1998	
	A132	5,725,788		Maracas et al.	03-10-1998	
	A133	5,726,548		Chiba et al.	03-10-1998	
	A134	5,731,981		Simard	03-24-1998	
	A135	5,736,424		Prybyla et al.	04-07-1998	
	A136	5,743,998		Park	04-28-1998	
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	A137	5,747,102		Smith et al.	05-05-1998	
	A138	5,753,014		Van Rijn	05-19-1998	
	A139	5,760,500		Kondo et al.	06-02-1998	
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	A154	5,895,263		Carter et al.	04-20-1999	
	A155	5,900,160		Whitesides et al.	05-04-1999	
	A156	5,907,782		Wu	05-25-1999	
	A157	5,912,049		Shirley	06-15-1999	
	A158	5,926,690		Toprac et al.	07-20-1999	
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	A161	5,948,219		Rohner	09-07-1999	
	A162	5,948,470		Harrison et al.	09-07-1999	
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	A164	5,952,127		Yamanaka	09-14-1999	
	A165	5,988,859		Kirk	11-23-1999	
	A166	6,033,977		Gutsche et al.	03-07-2000	
	A167	6,035,805		Rust	03-14-2000	
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	A169	6,038,280		Rossiger et al.	03-14-2000	
	A170	6,039,897		Lochhead et al.	03-21-2000	
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	A171	6,046,056		Parce et al.	04-04-2000	
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				Application Number	10/789,319
				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	7	of	25	Attorney Docket Number	P121-63-03

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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Application Number	10/789,319
Filing Date	02/27/2004
First Named Inventor	Xu et al.
Group Art Unit	1712
Examiner Name	Zimmer, Marc S.
Attorney Docket Number	P121-63-03

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			Filing Date	02/27/2004	
			First Named Inventor	Xu et al.	
			Group Art Unit	1712	
			Examiner Name	Zimmer, Marc S.	
			Attorney Docket Number	P121-63-03	
Sheet	9	of	25		

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				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
				Attorney Docket Number	P121-63-03
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First Named Inventor	Xu et al.
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		Office ³	Number ⁴	Kind Code ⁵ (if known)				
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				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	13	of	25	Attorney Docket Number	P121-63-03

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	A377	BENDER et al., "Fabrication of Nanostructures using a UV-based Imprint Technique," Microelectronic Engineering 53, January 1, 2000, pp. 233-236.	

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				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	14	of	25	Attorney Docket Number	P121-63-03

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	A378	BENDER et al., "Multiple Imprinting in UV-based Nanoimprint Lithography: Related Material Issues.", Microelectronic Engineering 61 – 62, January 1, 2002, pp. 407-413.	
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	A384	CHOU et al., "Imprint Lithography with Sub-10 nm Feature Size and High Throughput.", Microelectronic Engineering 35, January 1, 1997, pp. 237-240.	
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	A386	CHOU et al., "Lithographically Induced Self-assembly of Periodic Polymer Micropillar Arrays.", J. Vac. Sci. Technol., November 1, 1999, B 17(6), pp. 3197-3202.	
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	A400	GOLDFARB et al., "Compliant Micromanipulator Design for Scaled Bilateral Telemanipulation of Small-Scale Environments.", ASME International Mechanical Engineering Conference and Exposition, November 1, 1998, DSC-Vol. 64, pp. 213-218.	
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	A407	HIRAI et al., "Mold Surface Treatment for Imprint Lithography.", Journal of Photopolymer Science and Technology, August 1, 2001, Vol. 14, No. 3, pp. 457-462.	
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	A434	MERLET, "Parallel Manipulators: State of the Art and Perspectives.", Advanced Robotics, January 1, 1994, Vol. 8, pp. 589-596.	
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	A455	PERNETTE et al., "Design of Parallel Robots in Microbotics.", Robotica, January 1, 1997, Vol. 15, pp 417-420.	
	A456	PHYSIK INSTRUMENTS, "Hexapod Six-Axis Parallel Kinematics Robot", Nano Positioning, January 1, 1998, pp. 8.4 – 8.5.	
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	A464	ROOS et al., "Nanoimprint Lithography with a Commercial 4 Inch Bond System for Hot Embossing.", Proceedings of SPIE, October 1, 2001, Vol. 4343, pp. 427-435.	
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				Filing Date	02/27/2004
				First Named Inventor	Xu et al.
				Group Art Unit	1712
				Examiner Name	Zimmer, Marc S.
Sheet	22	of	25	Attorney Docket Number	P121-63-03

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
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	A466	SAGIV, "Organized Monolayers by Absorption. 1. Formation and Structure of Oleophobic Mixed Monolayers on Solid Surfaces.", Journal of American Chemical Society/102:1, January 2, 1980.	
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	A477	TAJBAKHS et al., "Three-Degree-of-Freedom Optic Mount for Extreme Ultraviolet.", American Society for Precision Engineering, January 1, 1998, pp. 359-362.	
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	A482	TRILOGY SYSTEMS, "Linear Motors 310.", www.trilogysystems.com, January 1, 2001.	
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	A486	US Application No. 10/614,716, Filed 07-07-2003, SREENIVASAN et al., "A Conforming Template for Patterning Liquids Disposed on Substrates."	
	A487	US Application No. 10/666,527, Filed 09-18-03, BAILEY et al., "Imprint Lithography Templates having Alignment Marks."	

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	A488	US Application No. 10/677,639, Filed 10-02-03, MCMACKIN et al., "Single Phase Fluid Imprint Lithography Method."	
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	A499	US Application No. 60/394,458, Filed 07-08-2002, SREENIVASAN et al., "Method and Apparatus for Whole Wafer Planarization using Optical Flats and Light Curable Liquids."	
	A500	US Applications No. 10/616,294, Filed 07-09-2003, CHOI et al., "Systems for Magnification and Distortion Correction for Imprint Lithography Processes."	
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